

<b>L Number</b>	<b>Hits</b>	<b>Search Text</b>	<b>DB</b>	<b>Time stamp</b>
<b>1</b>	<b>629</b>	(electromechanical or microelectromechanical or electromachin\$3 or MEMS or MEM) same ((wet\$3 or liquid or chemical or wet\$chemical) near3 (etch\$4 or process or chemical))	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 12:17</b>
<b>3</b>	<b>0</b>	((electromechanical or microelectromechanical or electromachin\$3 or MEMS or MEM) same ((wet\$3 or liquid or chemical or wet\$chemical) near3 (etch\$4 or process or chemical))) and ((metal or metallic or metal\$7) near3 (film or layer))) and acclerometer	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 11:31</b>
<b>2</b>	<b>289</b>	((electromechanical or microelectromechanical or electromachin\$3 or MEMS or MEM) same ((wet\$3 or liquid or chemical or wet\$chemical) near3 (etch\$4 or process or chemical))) and ((metal or metallic or metal\$7) near3 (film or layer))	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 11:48</b>
<b>4</b>	<b>4333</b>	((polymer or polymeric) near3 substrate) same (mass or weight)	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 11:51</b>
<b>5</b>	<b>75</b>	((polymer or polymeric) near3 substrate) same (mass or weight)) same (spring or flexure or flexture or web)	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 11:54</b>
<b>8</b>	<b>1937</b>	((polymer or polymeric) near3 substrate) with (mass or weight))	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 11:54</b>
<b>9</b>	<b>18</b>	((polymer or polymeric) near3 substrate) with (mass or weight))) same (spring or flexure or flexture or web)	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 11:55</b>
<b>10</b>	<b>0</b>	((polymer or polymeric) near3 substrate) with (mass or weight))) same (accelerometer)	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 11:55</b>
<b>11</b>	<b>2</b>	((polymer or polymeric) near3 substrate) with (mass or weight))) and (accelerometer)	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 11:55</b>
<b>12</b>	<b>57</b>	(electromechanical or microelectromechanical or electromachin\$3 or MEMS or MEM) same ((polymer or polymeric) near3 substrate)	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 12:05</b>
<b>14</b>	<b>16</b>	(electromechanical or microelectromechanical or electromachin\$3 or MEMS or MEM) same ((spring or web or flexture or flexure) with ((metallic or metal or metallized or metallization) near3 (film or coat\$4 or cover\$4 or layer or top\$4)))	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 12:26</b>
<b>15</b>	<b>8</b>	accelerometer same ((spring or web or flexture or flexure) with ((metallic or metal or metallized or metallization) near3 (film or coat\$4 or cover\$4 or layer or top\$4)))	<b>USPAT; US-PGPUB</b>	<b>2003/11/07 13:07</b>

16	0	accelerometer same ((spring or web or flexure or flexure) with ((metallic or metal or metallized or metallization) near3 (film or coat\$4 or cover\$4 or layer or top\$4)))	EPO; JPO; DERWENT	2003/11/07 13:21
19	3	accelerometer same ((liquid near3 crystal near3 polymer) or LCP or polyamide)	USPAT; US-PGPUB	2003/11/07 13:23
20	1	accelerometer same ((liquid near3 crystal near3 polymer) or LCP or polyamide)	EPO; JPO; DERWENT	2003/11/07 13:25